PLUS

	L #	Hits	Search Text	DBs	Time Stamp	Typ
1	L1	50	("5377016" "5535017" "5402350" "5495417" "5694325" "6788985" "5420696" "5295065" "5980086" "5831859" "5841676" "6052319" "6148279" "6421287" "6604012" "6662150" "6084353" "5239272" "5283534" "5471313" "5548245" "5581153" "5606221" "5687303" "5990621" "6006013" "6104239" "6239829" "6256104" "6327043" "6356742" "6416096" "6429948" "6450712" "6614158" "6671064" "6724153" "4162520" "4074352" "4106092" "5261047" "5276799" "5303341" "5307458" "5349647" "5576847" "5970224" "5970223" "5255181" "5291394").pn.	USPAT	2004/12/10 19:22	BRS

10/798670

10798670_CLS

Most Frequently Occurring Classifications of Patents Returned From A Search of 10798670 on November 26, 2004

Original Classifications

5 358/1.15
3 315/5
3 330/45
3 358/1.16
3 700/121
2 358/1.17
2 365/201
2 700/101
2 705/8

Cross-Reference Classifications

5 315/5.39
4 315/5.37
3 330/45
3 358/1.9
3 700/99
2 333/230
2 345/536
2 345/619
2 358/1.14
2 358/296
2 358/404
2 358/406
2 358/444
2 358/448
2 358/468
2 375/296
2 700/100
2 700/109
2 700/121

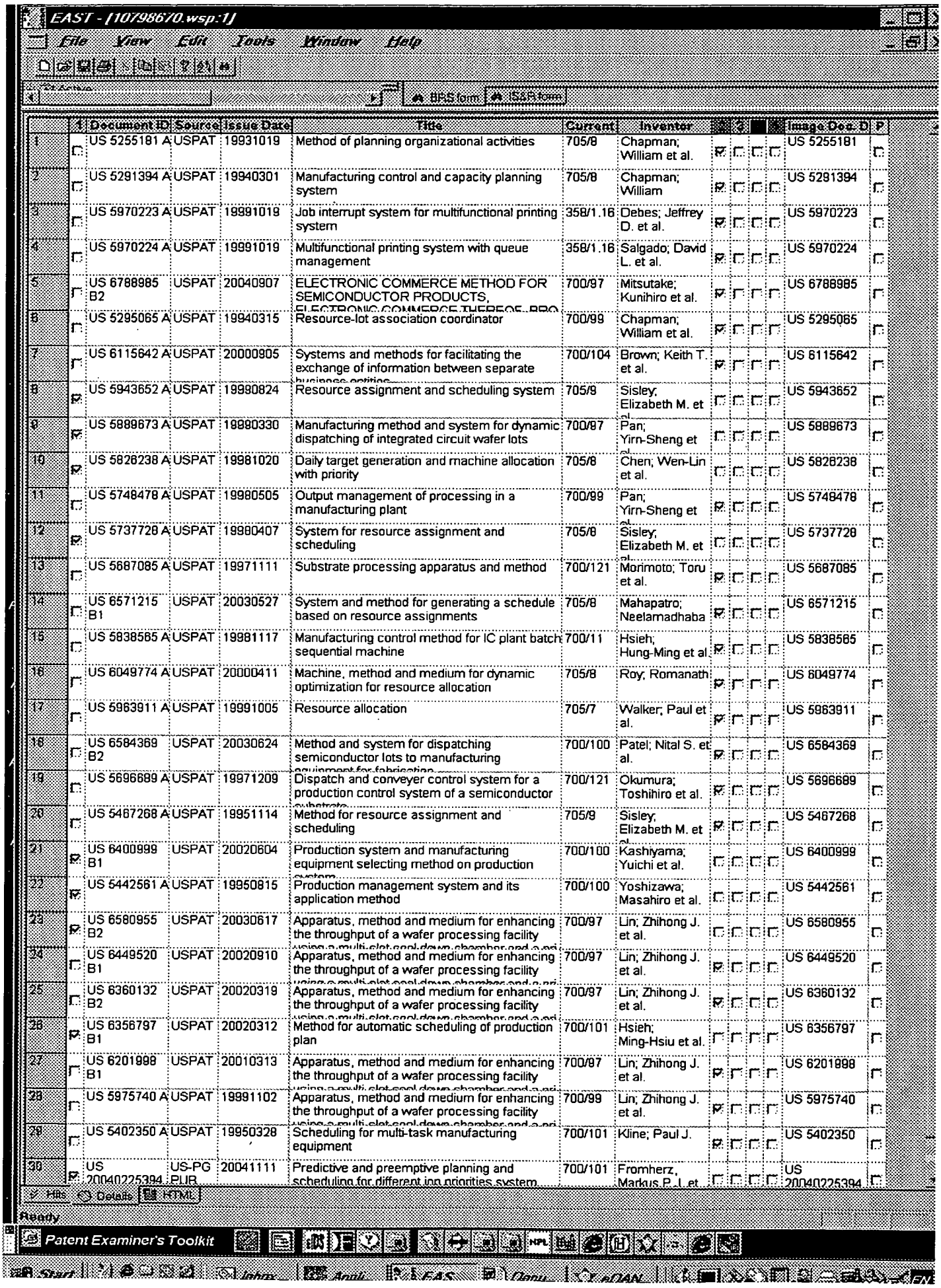
Combined Classifications

6 330/45
6 358/1.15
5 315/5.39
5 700/121
4 315/5
4 315/5.37
4 358/1.16
4 700/99
3 358/1.17
3 358/1.9
3 358/296
3 358/444
3 358/448
3 358/468
3 705/8
2 333/230
2 345/502
2 345/536
2 345/619
2 358/1.14
2 358/404
2 358/406
2 365/201
2 375/296
2 700/100
2 700/101
2 700/109
2 702/84
2 703/22

EAST

	L #	Hits	S arch Text	DBs	Time Stamp	Type
1	L2	49	("5255181").URPN.	USPAT	2004/12/10 20:20	BRS
2	L3	26	("5291394").URPN.	USPAT	2004/12/10 20:31	BRS
3	L4	16	("5295065").URPN.	USPAT	2004/12/10 20:35	BRS
4	L5	35	("5737728").URPN.	USPAT	2004/12/10 20:40	BRS
5	L6	41553	(equipment OR resource OR machine OR device) WITH (schedul$3 OR allocat$3 OR sequenc$3) SAME (fabricat$3 OR manufactur$3 OR assembl$3 OR produc$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/10 20:42	BRS
6	L7	610	L6 SAME priority	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/10 20:42	BRS
7	L8	48	L7 SAME (stag$3 OR remov$3 OR paus$3 OR defer$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/10 21:07	BRS
8	L9	70	("5442561").URPN.	USPAT	2004/12/10 20:50	BRS
9	L10	68	L7 SAME (interrupt$3 OR bypass$3 OR "by-pass$3")	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2004/12/10 21:07	BRS

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EAST - [10798670.wsp:1]
File View Edit Tools Window Help
IPR5 form ISSR form
Document ID Source Issue Date Title Current Inventor Image Doc. D
1 US 5255181 A USPAT 19931019 Method of planning organizational activities 705/8 Chapman; William et al. US 5255181
2 US 5291394 A USPAT 19940301 Manufacturing control and capacity planning system 705/8 Chapman; William US 5291394
3 US 5970223 A USPAT 19991019 Job interrupt system for multifunctional printing system 358/1.16 Debes; Jeffrey D. et al. US 5970223
4 US 5970224 A USPAT 19991019 Multifunctional printing system with queue management 358/1.16 Salgado; David L. et al. US 5970224
5 US 6788985 B2 USPAT 20040907 ELECTRONIC COMMERCE METHOD FOR SEMICONDUCTOR PRODUCTS, 700/97 Mitsutake; Kunihiro et al. US 6788985
6 US 5295065 A USPAT 19940315 Resource-lot association coordinator 700/99 Chapman; William et al. US 5295065
7 US 6115642 A USPAT 20000905 Systems and methods for facilitating the exchange of information between separate 700/104 Brown; Keith T. et al. US 6115642
8 US 5943652 A USPAT 19990824 Resource assignment and scheduling system 705/9 Sisley; Elizabeth M. et US 5943652
9 US 5889673 A USPAT 19990330 Manufacturing method and system for dynamic dispatching of integrated circuit wafer lots 700/97 Pan; Yirn-Sheng et US 5889673
10 US 5826238 A USPAT 19981020 Daily target generation and machine allocation with priority 705/8 Chen; Wen-Lin et al. US 5826238
11 US 5748478 A USPAT 19980505 Output management of processing in a manufacturing plant 700/99 Pan; Yirn-Sheng et US 5748478
12 US 5737728 A USPAT 19980407 System for resource assignment and scheduling 705/8 Sisley; Elizabeth M. et US 5737728
13 US 5687085 A USPAT 19971111 Substrate processing apparatus and method 700/121 Morimoto; Toru et al. US 5687085
14 US 6571215 B1 USPAT 20030527 System and method for generating a schedule based on resource assignments 705/8 Mahapatro; Neelamadhaba US 6571215
15 US 5838565 A USPAT 19981117 Manufacturing control method for IC plant batch sequential machine 700/11 Hsieh; Hung-Ming et al. US 5838565
16 US 6049774 A USPAT 20000411 Machine, method and medium for dynamic optimization for resource allocation 705/8 Roy; Romanath US 6049774
17 US 5963911 A USPAT 19991005 Resource allocation 705/7 Walker; Paul et al. US 5963911
18 US 6584369 B2 USPAT 20030624 Method and system for dispatching semiconductor lots to manufacturing 700/100 Patel; Nital S. et al. US 6584369
19 US 5696689 A USPAT 19971209 Dispatch and conveyer control system for a production control system of a semiconductor 700/121 Okumura; Toshihiro et al. US 5696689
20 US 5467268 A USPAT 19951114 Method for resource assignment and scheduling 705/9 Sisley; Elizabeth M. et US 5467268
21 US 6400999 B1 USPAT 20020604 Production system and manufacturing equipment selecting method on production 700/100 Kashiyama; Yuichi et al. US 6400999
22 US 5442561 A USPAT 19950815 Production management system and its application method 700/100 Yoshizawa; Masahiro et al. US 5442561
23 US 6580955 B2 USPAT 20030617 Apparatus, method and medium for enhancing the throughput of a wafer processing facility 700/97 Lin; Zhihong J. et al. US 6580955
24 US 6449520 B1 USPAT 20020910 Apparatus, method and medium for enhancing the throughput of a wafer processing facility 700/97 Lin; Zhihong J. et al. US 6449520
25 US 6360132 B2 USPAT 20020319 Apparatus, method and medium for enhancing the throughput of a wafer processing facility 700/97 Lin; Zhihong J. et al. US 6360132
26 US 6356797 B1 USPAT 20020312 Method for automatic scheduling of production plan 700/101 Hsieh; Ming-Hsiu et al. US 6356797
27 US 6201998 B1 USPAT 20010313 Apparatus, method and medium for enhancing the throughput of a wafer processing facility 700/97 Lin; Zhihong J. et al. US 6201998
28 US 5975740 A USPAT 19991102 Apparatus, method and medium for enhancing the throughput of a wafer processing facility 700/99 Lin; Zhihong J. et al. US 5975740
29 US 5402350 A USPAT 19950328 Scheduling for multi-task manufacturing equipment 700/101 Kline; Paul J. US 5402350
30 US 20040225394 US-PG PUB 20041111 Predictive and preemptive planning and scheduling for different ing priorities system 700/101 Fromherz, Markus P. J. et US 20040225394
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